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CONFIRMATION NO. 9360

SERIAL NUMBER	FILING OR 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
10/686,584	10/17/2003	356	2877	501.33745CX4
<b>RULE</b>				
<b>APPLICANTS</b> Shunji Maeda, Yokohama-shi, JAPAN; Yasuhiko Nakayama, Yokohama-shi, JAPAN; Minoru Yoshida, Yokohama-shi, JAPAN; Hitoshi Kubota, Fujisawa-shi, JAPAN; Kenji Oka, Fujisawa-shi, JAPAN;				
<b>** CONTINUING DATA *****</b> This application is a CON of 10/098,478 03/18/2002 PAT 7,061,600 which is a CON of 09/588,201 06/06/2000 PAT 6,404,498 which is a CON of 09/107,432 06/30/1998 PAT 6,263,099 which is a CON of 08/539,886 10/06/1995 PAT 5,774,222				
<b>** FOREIGN APPLICATIONS *****</b> JAPAN 6-268130 10/07/1994				
<b>IF REQUIRED, FOREIGN FILING LICENSE GRANTED</b> <b>** 01/12/2004</b>				
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> Met after Allowance Verified and Acknowledged <input checked="" type="checkbox"/>		STATE OR COUNTRY JAPAN	SHEETS DRAWING 30	TOTAL CLAIMS 20 25
ADDRESS 020457		INDEPENDENT CLAIMS 4 5		
<b>TITLE</b> Manufacturing method of semiconductor substrate and method and apparatus for inspecting defects of patterns of an object to be inspected				
<b>FILING FEE RECEIVED</b> 1032	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue ) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	